

WAFER CASSETTE HANDLE

ABSTRACT

The present invention provides a wafer cassette handle, which is disposed in a wafer cassette and comprises a body and a grip part. The body is disposed on an outer surface of the wafer cassette and has a first surface and a second surface opposite to the first surface. In addition, the first surface faces the outer surface. The grip part is disposed on the second surface of the body and has a bottom surface, which is flat. The first surface of the body has at least a propping bump against the outer surface of the wafer cassette. By using the present invention, the sensing ability of the sensor at the front end of a manipulator on the grip part is superior. Besides, the stress in the wafer cassette handle and at the junction between the wafer cassette handle and the wafer cassette can be dispersed for avoiding damaging the wafer cassette handle.

Figure 4